

Fabrication of sub-50 nm Solid-State Nanostructures Based on Dip-Pen Nanolithography

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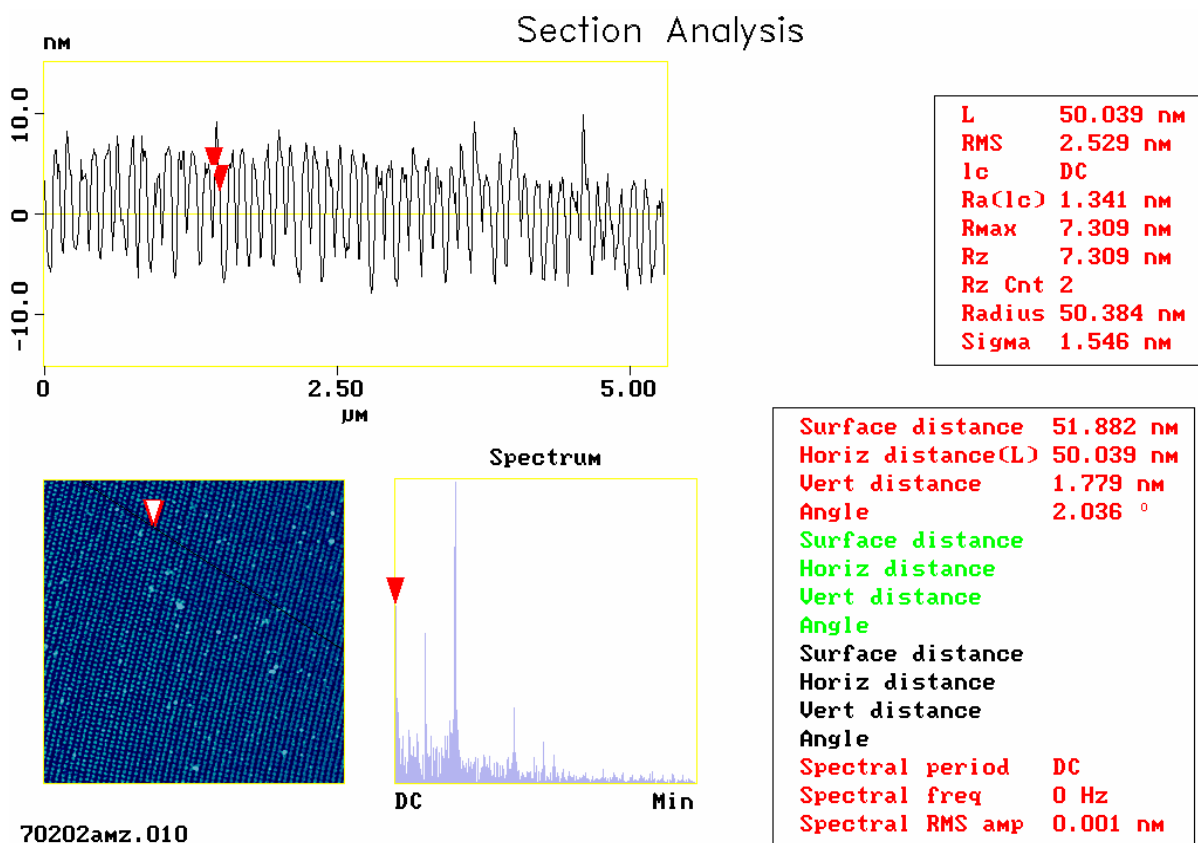


Figure S1A. Section Analysis of the etched Au nanoarrays in Figure 1A.

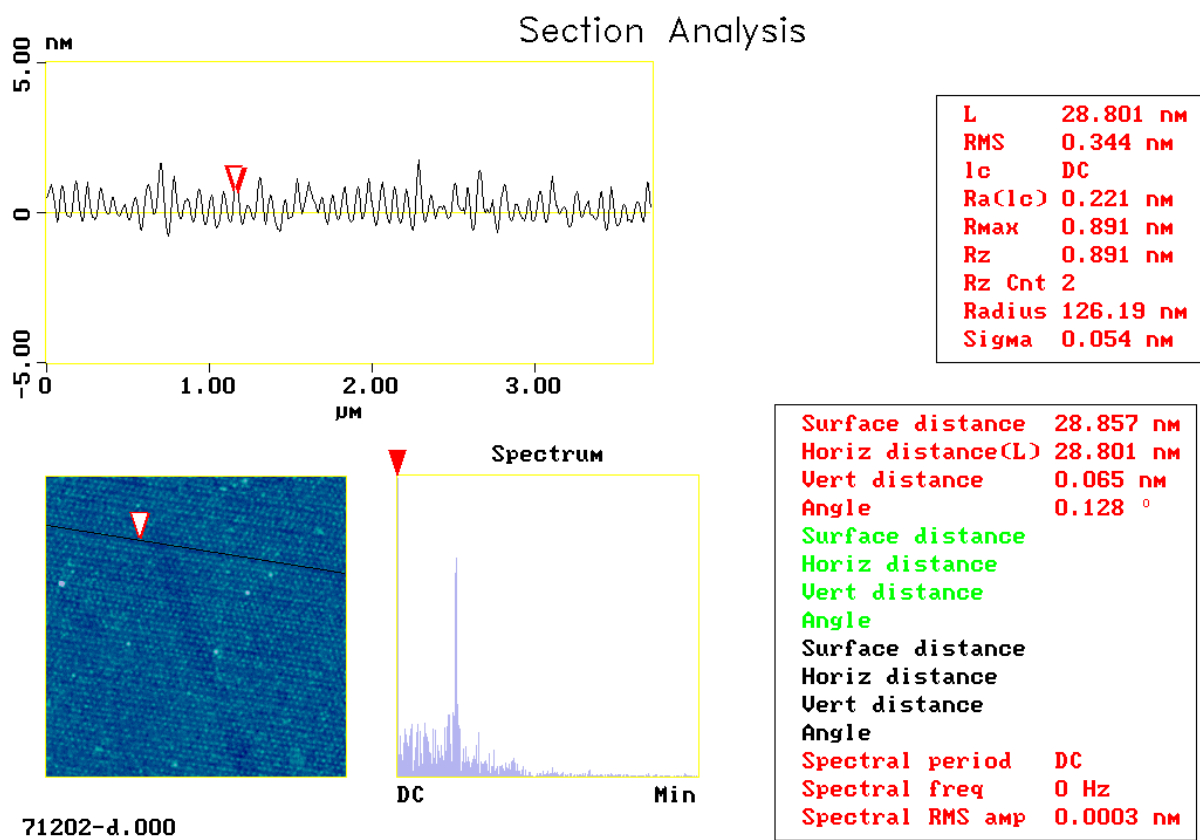


Figure S1B. Section Analysis of the etched Au nanoarrays in Figure 1C. The average diameter of the etched Au dots is 25 ± 5 nm.

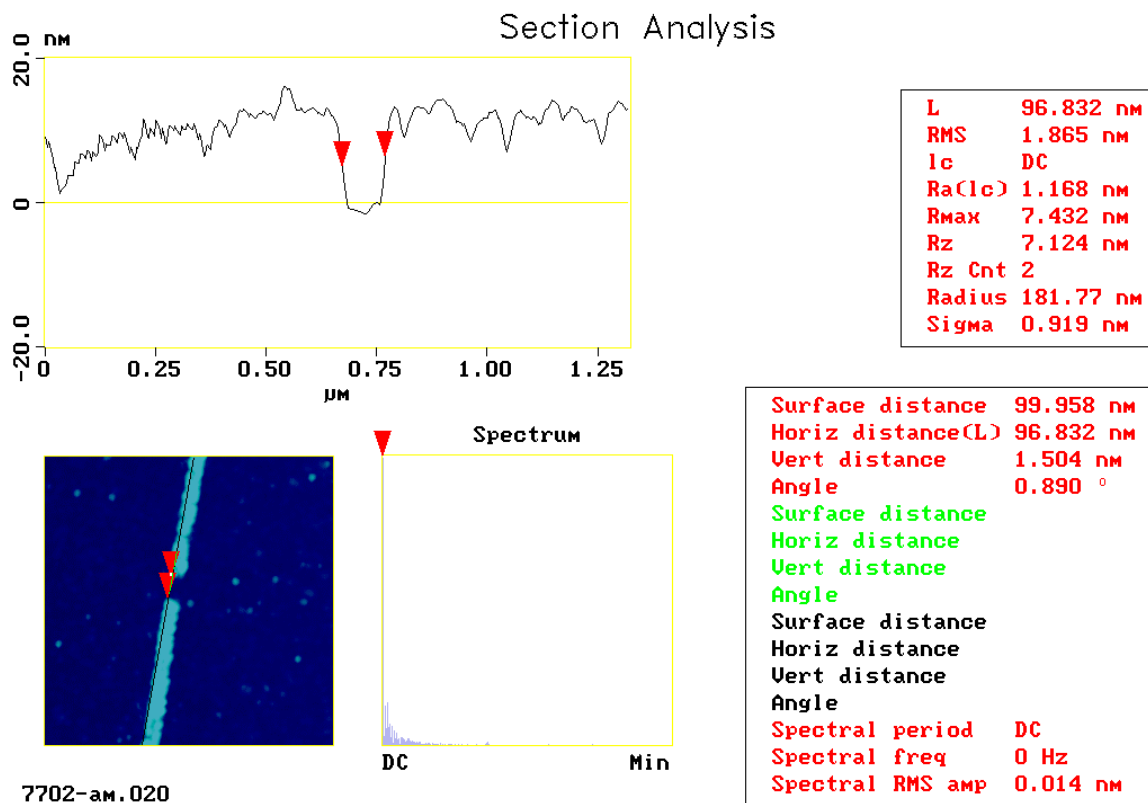


Figure S2A. Section Analysis of the etched Au nanogap in Figure 2A.

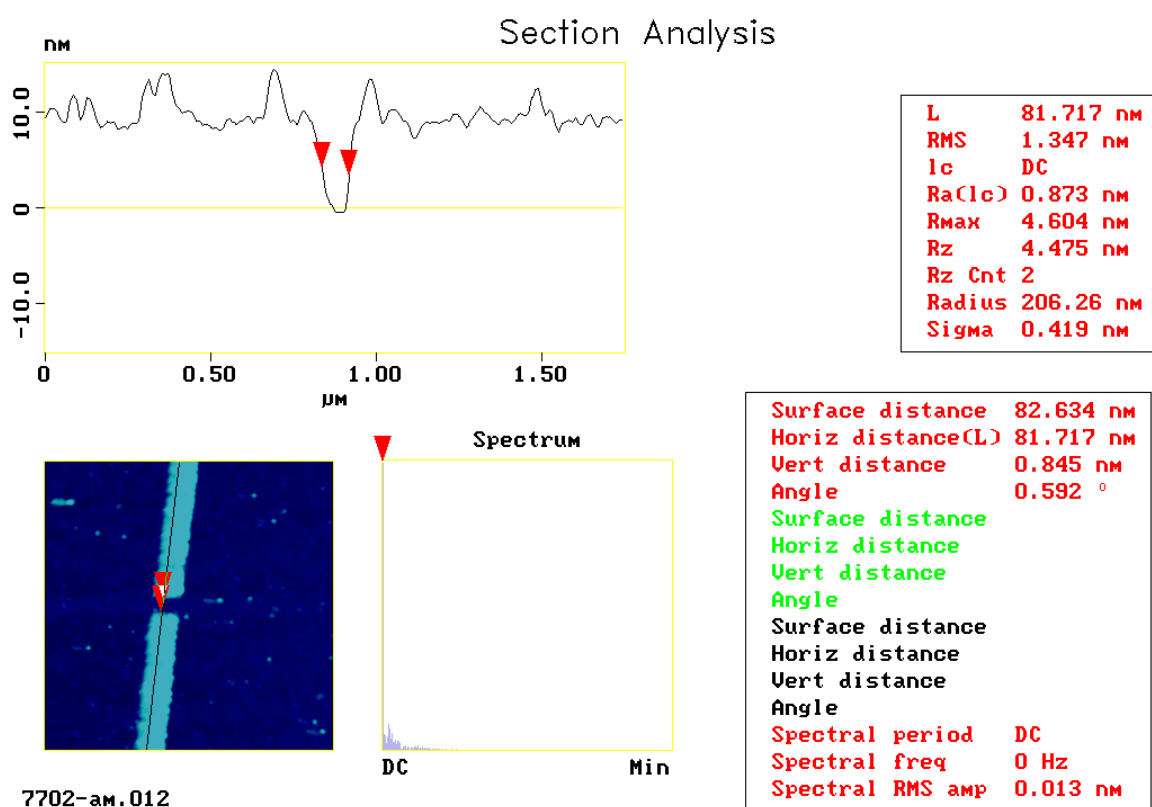


Figure S2B. Section Analysis of the etched Au nanogap in Figure 2B.

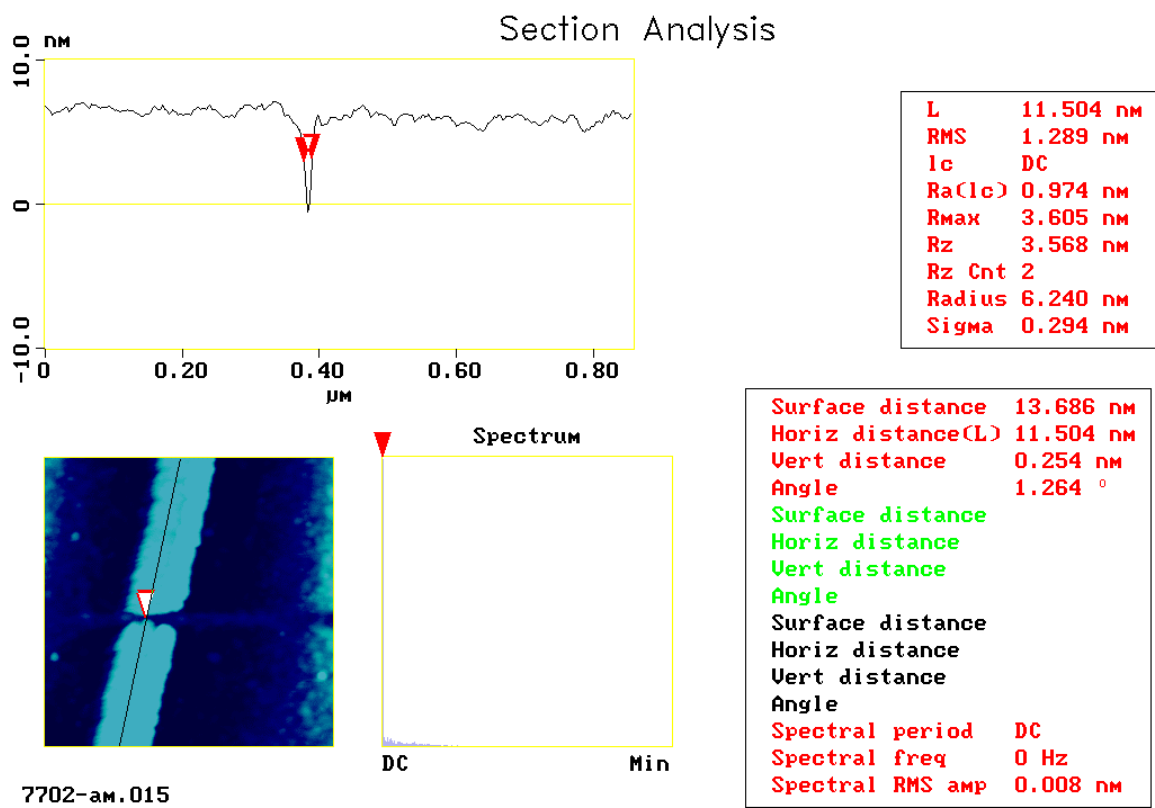


Figure S2C. Section Analysis of the etched Au nanogap in Figure 2C.